



## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroyoshi TOMINAGA et al.

Group Art Unit: 3723

Application No.:

10/500,278

Examiner:

M. RACHUBA

Filed: June 29, 2004

Docket No.: 120214

For:

WAFER DOUBLE-SIDE POLISHING APPARATUS AND DOUBLE-SIDE

POLISHING METHOD

## **AMENDMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In reply to the March 9, 2007 Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.